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**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 2823**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Seiichi MIYAZAKI

Group Art Unit: 2823

Application No.: 09/913,334

Examiner: G. Fourson

Filed: August 13, 2001

Docket No.: 110386

For: ETCHANT, ETCHING METHOD AND SEMICONDUCTOR SILICON WAFER

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

*Please enter 9/17/04*

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the June 8, 2004 Office Action, please consider the following:

**Amendments to the Claims as reflected in the listing of claims;**

**Remarks.**